

POLISHING APPARATUS AND CALIBRATION METHOD

ABSTRACT

An output of an eddy current sensor includes an impedance component. A film thickness measuring apparatus obtains film thickness information from the impedance component. Using a non-linear function between the film thickness information and the film thickness, the film thickness is obtained from the film thickness information. When a resistance component and a reactance component of the impedance component are associated with respective axes of a coordinate system having two orthogonal coordinate axes, the film thickness information is a reciprocal of a tangent of an impedance angle which is an angle formed by a straight line connecting a point on the coordinate system corresponding to the impedance component and a predetermined reference point, and a predetermined straight line.

Representative drawing: Fig. 2